

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Confirmation No.: 8995
Makiko KITAZOE et al. Group Art Unit: 1792
Application No.: 10/593,444 Examiner: Joseph Albert MILLER, Jr.
Filed: February 5, 2007 Attorney Docket No.: 029567-00011
For: UNIT-LAYER POST-PROCESSING CATALYST CHEMICAL-VAPOR
DEPOSITION APPARATUS AND ITS FILM FORMING METHOD

RESPONSE WITH A REQUEST FOR CONTINUED EXAMINATION

Mail Stop AFTER FINAL
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

January 11, 2010

Sir:

In reply to the outstanding Office Action dated September 15, 2009, please amend the application as shown on the following pages. The period for response is extended by one month, from December 15, 2009 to January 15, 2010, and the payment of the appropriate fee is submitted herewith via EFS. A Request for Continued Examination and the required fee are also submitted herewith.

Amendments to the Claims begin on page 2.

Remarks begin on page 8.

Conclusion begins on page 12.